

## ABSTRACT

A component-mounted substrate (3B) moved to a specified substrate position (P3) by a substrate holding-and-moving device (26, 28) is delivered from the top of the substrate holding-and-moving device to a substrate discharge holder (38, 39), and then while the substrate discharge holder is not moved, the substrate holding-and-moving device is moved to another substrate position (P2), where a new substrate (3A) is received. Consequently, a later-executed movement operation for moving the new substrate to a substrate mounting region (P0) by the substrate holding-and-moving device and a transfer operation for transferring the component-mounted substrate to an unloader unit (34) by the substrate discharge holder may be performed in parallel with each other without being influenced from each other's operation.